

<b>Notice of References Cited</b>		Application/Control No.	Applicant(s)/Patent Under Reexamination JAHNS ET AL.	
		Examiner Douglas N Washburn	Art Unit 2863	Page 1 of 2

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5,642,296	06-1997	Saxena, Sharad	702/84
	B	US-5,658,423	08-1997	Angell et al.	438/9
	C	US-5,711,843	01-1998	Jahns, Gary L.	156/345.24
	D	US-6,238,937	05-2001	Toprac et al.	438/9
	E	US-6,368,975	04-2002	Balasubramhanya et al.	438/706
	F	US-6,415,276	07-2002	Heger et al.	706/52
	G	US-6,419,846	07-2002	Toprac et al.	216/60
	H	US-6,521,080	02-2003	Balasubramhanya et al.	156/345.24
	I	US-6,564,114	05-2003	Toprac et al.	700/121
	J	US-6,582,618	06-2003	Toprac et al.	216/59
	K	US-6,603,538	08-2003	Oluseyi et al.	356/72
	L	US-6,675,137	01-2004	Toprac et al.	703/2
	M	US-2003/0136511	07-2003	Balasubramhanya et al.	156/345.25

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	White, D; Boning, D; Butler, S; Barna, G; "Spatial characterization of wafer state using principal component advanced analysis of optical emission spectra in plasma etch"; IEEE Transactions on Semiconductor Manufacturing; Vol 10, Issue 1; 1997; pp 52-61
	V	Martin, E.B.; Morris, A.I.; Zhang, J.; "Process performance monitoring using multivariate statistical process control"; IEE Proceedings Control Theory and Applications; Vol 143, Issue 2; 1996; pp 132-144
	W	Lennox, B; "Recent experiences in the industrial exploitation of principal component based fault detection methods"; Proceedings IEEE International Symposium on Computer Aided Control System Design; 18-20 Sept. 2002; pp x
	X	Weighell, M.; Martin, E.B.; Morris, A.J.; "Fault diagnosis in industrial process manufacturing using MSPC"; IEE Colloquium on Fault Diagnosis in Process Systems (Digest No: 1997/174); April 1997; pp 4/1-4/3

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)

Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.

<b>Notice of References Cited</b>		Application/Control No.	Applicant(s)/Patent Under Reexamination	
		10/658,984	JAHNS ET AL.	
Examiner		Art Unit	2863	Page 2 of 2
Douglas N Washburn				

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Martin, E; Morris, A; "Multivariate statistics and neural networks in process fault detection"; IEE Colloquium on Qualitative and Quantitative Modelling Methods for Fault Diagnosis; 24 Apr 1995; pp 7/1-7/8
	V	Yinghua, Y; Ningyun, L; Fuli, W; Liling, M; "A new fault detection and diagnosis method based on principal component analysis in multivariate continuous processes"; Prcdngs 4th Wrld Cngrss on Intllght Cntrl and Auto; Vol 4; 10-14 June 2002; pp 3156-3160
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.